



(19)

Eur pâisches Patentamt

European Patent Office

Office européen des brevets



(11) EP 0 917 193 A1

(12)

EUROPEAN PATENT APPLICATION

(43) Date of publication:
19.05.1999 Bulletin 1999/20

(51) Int. Cl.⁶: H01L 21/762, H01L 21/20,
H01L 21/322

(21) Application number: 98121271.5

(22) Date of filing: 09.11.1998

(84) Designated Contracting States:
AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU
MC NL PT SE

Designated Extension States:
AL LT LV MK RO SI

(30) Priority: 10.11.1997 JP 307719/97

(71) Applicant: NEC CORPORATION
Tokyo (JP)

(72) Inventor: Okonogi, Kensuke
Minato-ku, Tokyo (JP)

(74) Representative:
Baronetzky, Klaus, Dipl.-Ing. et al
Patentanwälte
Dipl.-Ing. R. Splanemann, Dr. B. Reitzner, Dipl.-
Ing. K. Baronetzky
Tal 13
80331 München (DE)

(54) Laminated SOI substrate and producing method thereof

(57) An insulation film (2) is formed on a first single crystal silicon substrate (1), e.g., a hydrogen anneal substrate, an intrinsic gettering substrate and an epitaxial substrate. Hydrogen implantation is carried out from a surface of this insulation film, thereby forming a hydrogen implantation region in the first single crystal silicon substrate. Then, by carrying out a thermal treatment at 400 to 500°C, voids (4) are formed in the hydrogen

implantation region, and the first single crystal silicon substrate is cleaved therefrom. Next, the surface of the insulation film and a surface of a second single crystal silicon substrate (5) are laminated and then, they are subjected to a thermal treatment at 1,000°C or higher. With this method, a bad influence on a device can be reduced and a yield can be enhanced.

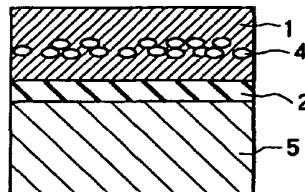


FIG. 2C

EP 0 917 193 A1

Description**BACKGROUND OF THE INVENTION****Field of the Invention**

5

[0001] The present invention relates to a laminated SOI (Silicon On Insulator) substrate preferable for a semiconductor device and a producing method thereof, and more particularly, to a laminated SOI substrate for reducing a bad influence on a device, and a producing method thereof.

Description of the Related Art

15

[0002] As a method for producing a super thin film SOI substrate by a lamination technique, there is known a smart-cut process utilizing a phenomenon that a semiconductor substrate is cleaved by void formed by charging a large amount of hydrogen (Proceedings 1996 IEEE International SOI conference, p152). Figs.1A to 1E are sectional views sequentially showing a producing method of the SOI substrate by the conventional smart-cut process.

[0003] In the producing method of the SOI substrate according to the conventional smart-cut process, silicon film dioxide 22 which is an insulation is first formed on a single crystal silicon substrate 21 as shown in Fig.1A. A surface area of the single crystal silicon substrate 21 will be a device forming area finally. On the surface area, oxygen deposition or crystal defect region 28 such as nucleus of the oxygen deposition which is called a grown-in defect as a general term exists.

[0004] Next, as shown in Fig.1B, hydrogen ion is ion implanted from a surface of the silicon film dioxide 22 by a dose amount of about 10^{16} to 10^{17} (atoms/cm²). For this reason, a hydrogen implanted region 23 is formed in the single crystal silicon substrate 21.

[0005] Then, as shown in Fig.1C, a surface of the silicon film dioxide 22 and a surface of another single crystal silicon substrate 25 are laminated at a room temperature, and are subjected to a thermal treatment at 400 to 500°C, thereby forming voids 24 in the hydrogen implanted region 23.

[0006] At that time, as shown in Fig.1D, the single crystal silicon substrate 21 is cleaved by the voids 24 formed in the hydrogen implanted region 23.

[0007] Next, a thermal treatment at about 1,000°C or higher is carried out for several hours to strongly adhere the laminated surfaces of the silicon file dioxide 22 and the single crystal silicon substrate 25. Then, a surface of the cleaved single crystal silicon substrate 21 is polished to form a mirror surface to complete the SOI substrate.

[0008] Then, the SOI substrate produced in this manner is advanced to a device forming step.

[0009] However, in the laminated SOI substrate produced by the above-described conventional method,

there are problems that particles are generated in the device produced using the SOI substrate, or bonding leakage, element separation characteristic and pressure resistance of gate insulation film are deteriorated.

SUMMARY OF THE INVENTION

[0010] It is an object of the present invention to provide a laminated SOI substrate and a producing method thereof in which a bad influence on a device can be reduced and a yield can be enhanced.

[0011] A laminated SOI substrate according to the present invention comprises a first single crystal silicon substrate and a second single crystal silicon substrate laminated on each other with an insulation film interposed therebetween. In the laminated SOI substrate, the first single crystal silicon substrate has one kind of substrate selected from a group consisting of a hydrogen anneal substrate, an intrinsic gettering substrate and an epitaxial substrate.

[0012] In the present invention, hydrogen anneal substrate, intrinsic gettering substrate or epitaxial substrate is used as the first single crystal silicon substrate on which a device is to be formed. Since crystal defects on a surface area of these substrates are extremely few, voids are suppressed from being formed on the substrate during the producing process. Therefore, it is possible to reduce a bad influence on a device.

[0013] A producing method of a laminated SOI substrate according to the present invention comprises the steps of: forming an insulation film on a surface of a first single crystal silicon substrate; forming a hydrogen implantation region in the first single crystal silicon substrate by carrying out hydrogen implantation from a surface of the insulation film; and laminating the surface of the insulation film and a surface of a second single crystal silicon substrate. In this producing method of the laminated SOI substrate, the first single crystal silicon substrate has one kind of substrate selected from a group consisting of a hydrogen anneal substrate, an intrinsic gettering substrate and an epitaxial substrate.

[0014] In the producing method of the laminated SOI substrate according to the present invention, the first single crystal silicon substrate includes a crystal defect region at a certain depth from a surface thereof.

[0015] In the present invention, since the first single crystal silicon substrate includes the crystal defect region at a certain depth from a surface thereof. If the hydrogen implantation is carried out, hydrogen is concentrated on the crystal defect region to form the voids for cleaving the substrate. That is, since voids are not formed in other regions, it is possible to reduce a bad influence on a device.

[0016] The crystal defect region may include at least one kind of crystal defect selected from a group of misfit dislocation and oxygen deposition.

[0017] Further, in the present invention, a thermal treatment at a temperature of 1,000°C or higher may be

carried out after the step of laminating the surface of the insulation film and a surface of a second single crystal silicon substrate.

[0018] The misfit dislocation may be generated by forming, on a third single crystal silicon substrate, a single crystal silicon layer having a resistance higher than that of the third single crystal silicon substrate by epitaxial growth.

[0019] In order to solve the above problems, the present inventors repeated experiments, and as a result, they found that since the crystal defect region 28 (see Fig. 1A) existed irregularly in the single crystal silicon substrate 21 used in the conventional method, voids 24a were formed also in the crystal defect region 28 by the hydrogen implantation as shown in Fig.1C, and the voids 24a remained in the single crystal silicon substrate 21 which is an active layer of the SOI substrate as shown in Fig.1E and therefore, a bad influence was exerted on a device produced from this SOI substrate. That is, in the producing method of the laminated SOI substrate by this smart-cut process, it is important to control a place where the voids are formed by the hydrogen implantation. A place where the voids are formed should be a place away from a surface where the hydrogen is implanted by a distance corresponding to a range of the hydrogen. However, if there is a region around such a place where hydrogen ion such as defect is prone to concentrate, voids may be formed in such a region. Thereupon, it is necessary to control the crystallinity on the surface of the basic single crystal silicon substrate. In the present invention, a place where the voids are formed is controlled by improving the crystallinity on the surface of the basic single crystal silicon substrate.

[0020] With this feature, according to the present invention, the voids are formed in a predetermined position of the semiconductor silicon substrate, and the semiconductor silicon substrate is cleaved in the position where the voids are formed and therefore, remained voids can be reduced. Thus, a bad influence on a device can be reduced and a yield can be enhanced.

BRIEF DESCRIPTION OF THE DRAWINGS

[0021]

Figs.1A to 1E are sectional views sequentially showing a producing method of the SOI substrate by a conventional smart-cut process;

Figs.2A to 2E are sectional views sequentially showing a producing method of a laminated SOI substrate according to a first embodiment of the present invention; and

Figs.3A to 3E are sectional views sequentially showing a producing method of the laminated SOI substrate according to a second embodiment of the present invention.

DESCRIPTION OF THE PREFERRED EMBODIMENTS

[0022] Preferred embodiments of the present invention will be explained concretely with reference to the accompanying drawings below.

[0023] Figs.2A to 2E are sectional views sequentially showing a producing method of a laminated SOI substrate according to a first embodiment of the present invention. In the method of the present embodiment, as a single crystal silicon substrate 1 in which hydrogen is implanted, a substrate having no grown-in defect and no oxygen deposition on a surface of the substrate and no defect region (DZ) 6 exists on surface area as shown in Fig.2A, such as a hydrogen anneal substrate, an intrinsic gettering (IG) substrate or an epitaxial substrate is used. The hydrogen anneal substrate is prepared by annealing a single crystal silicon material formed by FZ method or the like at 1,200°C for one hour in 100% hydrogen atmosphere for example. First, silicon film dioxide 2 which is an insulation material is formed on the single crystal silicon substrate 1.

[0024] Then, hydrogen ion is ion implanted from a surface of the silicon film dioxide 2 by a dose amount of about 10^{16} to 10^{17} (atoms/cm²). With this operation, a hydrogen implantation region 3 is formed in only a projection range region of the single crystal silicon substrate 1.

[0025] Then, as shown in Fig.2C, a surface of the silicon film dioxide 2 and a surface of another single crystal silicon substrate 5 are laminated at a room temperature, and are subjected to a thermal treatment at 400 to 500°C, thereby forming a large number of voids 4 in the hydrogen implanted region 3 at high density.

[0026] At that time, as shown in Fig.2D, the single crystal silicon substrate 1 is cleaved by the voids 4 formed in the hydrogen implanted region 3. In the present embodiment, since there is no crystal defect region on the surface area of the single crystal silicon substrate 1, it is possible to prevent the voids from remaining in the single crystal silicon substrate 1 unlike the conventional method.

[0027] Next, a thermal treatment at about 1,000°C or higher is carried out for several hours to strongly adhere the laminated surfaces of the silicon film dioxide 2 and the single crystal silicon substrate 5. Then, as shown in Fig.2E, a surface of the cleaved single crystal silicon substrate 1 is polished to form a mirror surface to complete the SOI substrate.

[0028] The SOI substrate produced in this manner has a structure shown in Fig.2E, and voids do not exist therein. Therefore, when a device is produced from this SOI substrate, it is possible to prevent a bad influence from being exerted on the device characteristic.

[0029] Next, a method of a second embodiment of the present invention will be explained. Figs.3A to 3E are sectional views sequentially showing a producing method of a laminated SOI substrate according to the

second embodiment of the present invention. In the method of the present embodiment, as a single crystal silicon substrate 11 in which hydrogen is implanted, a substrate provided at its surface area with a misfit dislocation region 17 in which a misfit dislocation is formed. The single crystal silicon substrate 11 having the misfit dislocation region 17 can be easily formed by forming a high resistance single crystal silicon layer on a low resistance substrate by epitaxial growth, or by allowing a single crystal silicon to epitaxially grow on SiGe layer, for example. First, a silicon film dioxide 12 which is an insulation material is formed on the single crystal silicon substrate 11.

[0030] Then, as shown in Fig.3B, hydrogen ion is ion implanted from a surface of the silicon film dioxide 12 by a dose amount of about 10^{16} to 10^{17} (atoms/cm²). With this operation, a hydrogen implantation region 13 is formed in only a projection range region of the single crystal silicon substrate 11 and the misfit dislocation region 17.

[0031] Then, as shown in Fig.3C, a surface of the silicon film dioxide 12 and a surface of another single crystal silicon substrate 15 are laminated at a room temperature, and are subjected to a thermal treatment at 400 to 500°C, thereby forming a large number of voids 14 in the hydrogen implanted region 13 at high density.

[0032] At that time, as shown in Fig.3D, the single crystal silicon substrate 11 is cleaved by the voids 14 formed in the hydrogen implanted region 13. In the present embodiment also, since there is no crystal defect region on the surface area of the single crystal silicon substrate 11, it is possible to prevent the voids from remaining in the single crystal silicon substrate 11 unlike the conventional method.

[0033] Next, a thermal treatment at about 1,000°C or higher is carried out for several hours to strongly adhere the laminated surfaces of the silicon film dioxide 12 and the single crystal silicon substrate 15. Then, as shown in Fig.3E, a surface of the cleaved single crystal silicon substrate 11 is polished to form a mirror surface to complete the SOI substrate.

[0034] The SOI substrate produced in this manner has a structure shown in Fig.3E, and voids do not exist therein. Therefore, as the SOI substrate produced by the method of the first embodiment, when a device is produced from this SOI substrate, it is possible to prevent a bad influence from being exerted on the device characteristic.

[0035] Although a substrate having the misfit dislocation region is used as the single crystal silicon substrate in the present embodiment, a substrate provided in its surface area with an oxygen deposition layer may be used. The substrate having the oxygen deposition layer is formed by cleansing a basic single crystal silicon substrate with hydrofluoric acid aqueous solution and then, by allowing a single crystal silicon layer to epitaxially grow on the basic single crystal silicon substrate.

Claims

1. A laminated SOI substrate, comprising:
5 a first single crystal silicon substrate (1);
a second single crystal silicon substrate (5);
and
10 an insulation film (2) interposed between said first and second single crystal silicon substrates,
characterized in that
15 said first single crystal silicon substrate (1) has one kind of substrate selected from a group consisting of a hydrogen anneal substrate, an intrinsic gettering substrate and an epitaxial substrate.
2. A producing method of a laminated SOI substrate, characterized by comprising the steps of:
20 forming an insulation film (2) on a surface of a first single crystal silicon substrate (1) which has one kind of substrate selected from a group consisting of a hydrogen anneal substrate, an intrinsic gettering substrate and an epitaxial substrate;
25 forming a hydrogen implantation region (3) in said first single crystal silicon substrate by carrying out hydrogen implantation from a surface of said insulation film; and
30 laminating said surface of said insulation film and a surface of a second single crystal silicon substrate (5).
3. A producing method of a laminated SOI substrate, characterized by comprising the steps of:
35 forming an insulation film (2) on a surface of a first single crystal silicon substrate (1) which includes a crystal defect region (17) at a certain depth from a surface thereof;
40 forming a hydrogen implantation region (3) in said first single crystal silicon substrate (1) by carrying out hydrogen implantation from a surface of said insulation film; and
45 laminating said surface of said insulation film and a surface of a second single crystal silicon substrate (5).
4. A producing method of a laminated SOI substrate according to claim 3, characterized in that said crystal defect region (17) includes at least one kind of crystal defect selected from a group of misfit dislocation and oxygen deposition.
50
5. A producing method of a laminated SOI substrate according to claim 2, characterized by further comprising a step of conducting a thermal treatment at
55

a temperature of 1,000°C or higher, after said step of laminating said surface of said insulation film and said surface of said second single crystal silicon substrate.

5

6. A producing method of a laminated SOI substrate according to claim 3, characterized by further comprising a step of conducting a thermal treatment at a temperature of 1,000°C or higher, after said step of laminating said surface of said insulation film and said surface of said second single crystal silicon substrate. 10
7. A producing method of a laminated SOI substrate according to claim 4, characterized in that said misfit dislocation is generated by forming, on a third single crystal silicon substrate, a single crystal silicon layer having a resistance higher than that of said third single crystal silicon substrate by epitaxial growth. 15 20

25

30

35

40

45

50

55

5

FIG. 1A

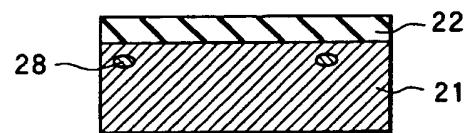


FIG. 1B

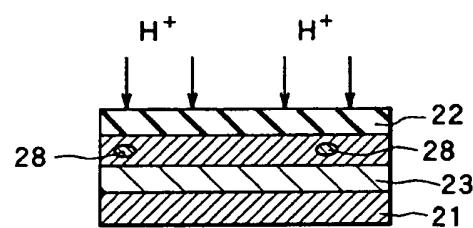


FIG. 1C

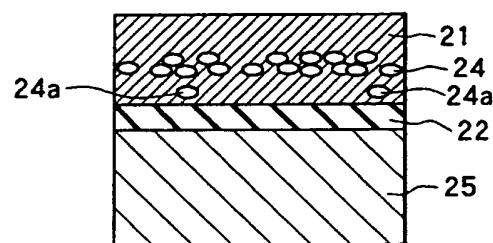


FIG. 1D

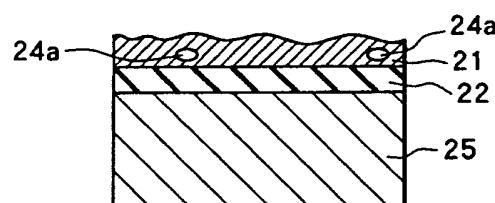


FIG. 1E

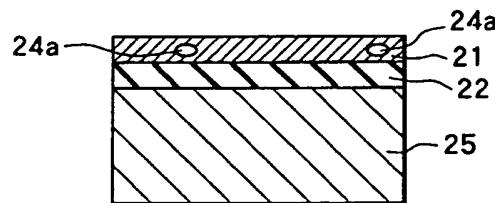


FIG. 2A

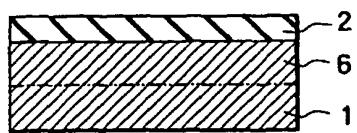


FIG. 2B

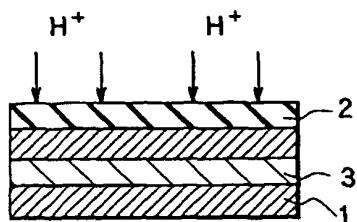


FIG. 2C

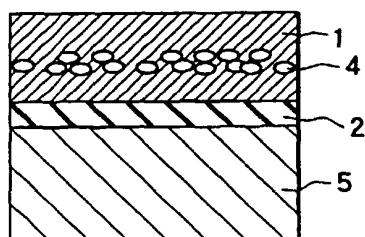


FIG. 2D

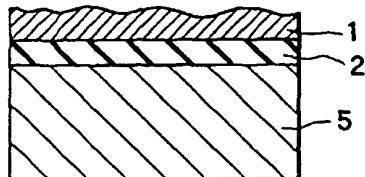


FIG. 2E

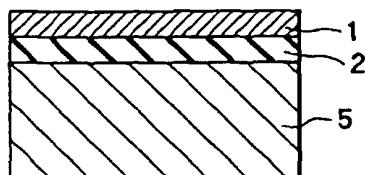


FIG. 3A

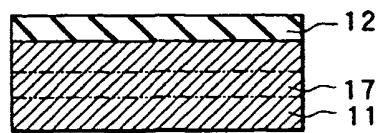


FIG. 3B

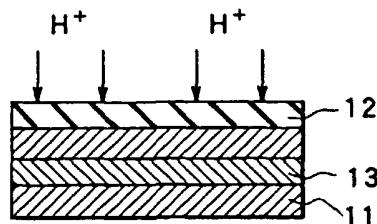


FIG. 3C

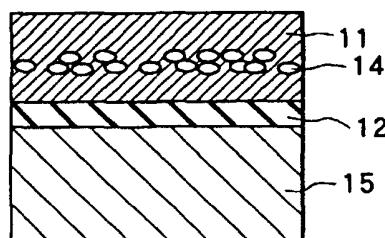


FIG. 3D

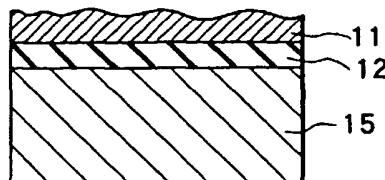
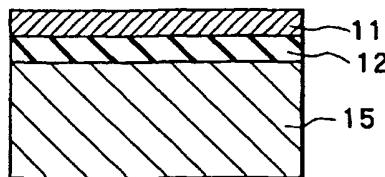


FIG. 3E





DOCUMENTS CONSIDERED TO BE RELEVANT			CLASSIFICATION OF THE APPLICATION (Int.Cl.6)
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	
X	EP 0 767 486 A (CANON KK) 9 April 1997 * abstract; figures 4,8 * * column 4, line 37 - line 51 * * column 8, line 4 - line 26 * * column 15, line 37 - line 44 * * column 28, line 5 - column 30, line 13 * ---	1-7	H01L21/762 H01L21/20 H01L21/322
X	DI CIOCCIO L ET AL: "Silicon carbide on insulator formation by the Smart-Cut(R) process" MATERIALS SCIENCE AND ENGINEERING B, vol. 46, no. 1-3, April 1997, page 349-356 XP004085343	1	
Y	* page 1 *	2-7	
X	US 5 476 813 A (NARUSE HIROSHI) 19 December 1995	1	
Y	* abstract; claims; figures * * column 1, line 61 - column 3, line 31 * * column 4, line 29 - column 5, line 17 * ---	2-7	
X	EP 0 352 801 A (FUJITSU LTD) 31 January 1990 * figure 3E * * column 1, line 14 - column 3, line 20 * ---	1	H01L
X	PATENT ABSTRACTS OF JAPAN vol. 097, no. 003, 31 March 1997 & JP 08 293589 A (HITACHI LTD), 5 November 1996 * abstract *	1	
Y	---	2-6	
		-/--	
The present search report has been drawn up for all claims			
Place of search	Date of completion of the search	Examiner	
BERLIN	12 February 1999	Hamdani, F	
CATEGORY OF CITED DOCUMENTS		T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document	
X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document			



European Patent
Office

EUROPEAN SEARCH REPORT

Application Number
EP 98 12 1271

DOCUMENTS CONSIDERED TO BE RELEVANT			CLASSIFICATION OF THE APPLICATION (Int.Cl.6)
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	
X	PATENT ABSTRACTS OF JAPAN vol. 097, no. 003, 31 March 1997 & JP 08 316442 A (MITSUBISHI MATERIALS CORP; MITSUBISHI MATERIALS SHILICON CORP), 29 November 1996 * abstract *	1	
Y	---	2-6	
X	PATENT ABSTRACTS OF JAPAN vol. 018, no. 299 (E-1558), 8 June 1994 & JP 06 061235 A (HITACHI LTD), 4 March 1994 * abstract *	1	
A	---	2-4	
X	PATENT ABSTRACTS OF JAPAN vol. 017, no. 264 (E-1370), 24 May 1993 & JP 05 006883 A (NIPPON STEEL CORP), 14 January 1993 * abstract *	1	
A	---	2	TECHNICAL FIELDS SEARCHED (Int.Cl.6)
A	US 5 633 174 A (LI JIANMING) 27 May 1997 * column 2, line 47 - column 3, line 30 * * column 4, line 13 - line 26 *	2,3	
A	EP 0 533 551 A (COMMISSARIAT ENERGIE ATOMIQUE) 24 March 1993 * abstract; claims; figures * * page 3, line 12 - page 5, line 19 *	1-7	
A	BRUEL M: "SILICON ON INSULATOR MATERIAL TECHNOLOGY" ELECTRONICS LETTERS, vol. 31, no. 14, 6 July 1995, page 1201/1202 XP000525349 * page - *	5,6	
	---	-/--	
The present search report has been drawn up for all claims			
Place of search BERLIN	Date of completion of the search 12 February 1999	Examiner Hamdani, F	
CATEGORY OF CITED DOCUMENTS		T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application I : document cited for other reasons & : member of the same patent family, corresponding document	
X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document			



DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int.Cl.6)
A	US 4 837 172 A (MIZUNO BUNJI ET AL) 6 June 1989 * column 1, line 6 - line 60 * -----	1,2	
The present search report has been drawn up for all claims			
Place of search	Date of completion of the search	Examiner	
BERLIN	12 February 1999	Hamdani, F	
CATEGORY OF CITED DOCUMENTS		T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document	
X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document			

ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.

EP 98 12 1271

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report.
The members are as contained in the European Patent Office EDP file on
The European Patent Office is in no way liable for these particulars which are merely given for the purpose of information.

12-02-1999

Patent document cited in search report		Publication date		Patent family member(s)	Publication date
EP 0767486	A	09-04-1997		JP 9162090 A CA 2187269 A CN 1159071 A US 5854123 A	20-06-1997 07-04-1997 10-09-1997 29-12-1998
US 5476813	A	19-12-1995		JP 7142502 A	02-06-1995
EP 0352801	A	31-01-1990		JP 2037771 A DE 68920657 D DE 68920657 T US 5063113 A US 5194395 A	07-02-1990 02-03-1995 22-06-1995 05-11-1991 16-03-1993
US 5633174	A	27-05-1997		US 5198371 A	30-03-1993
EP 0533551	A	24-03-1993		FR 2681472 A JP 5211128 A US 5374564 A	19-03-1993 20-08-1993 20-12-1994
US 4837172	A	06-06-1989		JP 63271942 A JP 2001053 C JP 7034478 B JP 63027063 A	09-11-1988 20-12-1995 12-04-1995 04-02-1988

EPO FORM P0458

For more details about this annex : see Official Journal of the European Patent Office, No. 12/82